

ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of Invention	METHOD OF PLANARIZING SPIN-ON MATERIAL LAYER AND MANUFACTURING PHOTORESIST LAYER
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Application Number : 10 / 711,379

Confirmation Number:

First Named Applicant: Jefferson Lu

Attorney Docket Number: 12474-US-PA

Art Unit:

Examiner:

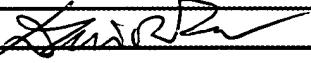
Search string: (6482716 or 6630397).pn

US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
PR	1	6482716	2002-11-19	Wohlfahrt et al.		438	427
PR	2	6630397	2003-10-07	Ding et al.		438	636

Signature

Examiner Name	Date
	4/26/05